

Oxford Instruments Plasma Technology

7ca dUbmDfcÚ`Y





CI ZcfX` bgrfi a YbhgD`Uga UHYWbc`c[mcZYfgÜYI JV`Yz`
Wz`bÚ[i fUV`Y`dfcWgg`hc`c`g`UbX``YUX]b[!YX[Y`dfcWgg`Yg`Zcf`
the precise, controllable and repeatable engineering of
micro- and nano-structures.

Our systems provide process solutions for nanometre layer epitaxial growth of compound semiconductor material, etching of nanometre sized features and the controlled growth of nanostructures. These solutions are based on core technologies in plasma-enhanced deposition and etch, ion-beam deposition and etch, atomic layer deposition and hydride vapour phase epitaxy. Products range from compact stand-alone systems for R&D, through batch tools and up to clustered cassette-to-cassette platforms for high-throughput production processing.

Our Markets:

- Semiconductor Electronics
- Display and Lighting
- Customer Service
- MEMS
- Research

Technologies:

-  Plasma Etch and Deposition
ICP, RIE, PECVD, ICP-CVD and sputtering etch and deposition processes using the **PlasmaPro**® product family
-  Atomic Layer Deposition (ALD)
FlexAL® and **OpAL**® ALD systems offering both thermal and plasma atomic layer deposition
-  Ion Beam Etch and Deposition
Ionfab® product family offering a versatile etch and deposition platform for a wide range of materials
-  Deep Silicon Etch
Our new **PlasmaPro Estrelas**100 system has been designed with the MEMS R&D market in mind

Customer Support

Oxford Instruments Plasma Technology is committed to supporting our customers' success. We recognise that this requires world-class products, complemented by world-class service and support. Our global service team is backed by regional offices, offering rapid worldwide support.

Head Office Address:
Oxford Instruments Plasma Technology
North End, Yatton, Bristol BS49 4AP, UK
Tel: +44 (0) 1934 837000 Fax: +44 (0) 1934 837001

For worldwide offices please visit our website: www.oxford-instruments.com/plasma

